

Form PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 39153/325 (F0853)		SERIAL NO. Unknown	
INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				APPLICANT Babcock et al.			
				FILING DATE Unknown		GROUP ART UNIT Unknown	

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U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>	
<div style="text-align: center; font-size: 1.5em;">DR</div>	Douglas Van Den Broeke, Transferring Phase-Shifting Mask Technology into Mainstream Manufacturing, printed from Internet address: http://www.semiconductorfabtech.com/f...s/lithography/articles/body5.225.php3 on October 6, 2000, 7 pages
<div style="text-align: center; font-size: 1.5em;">DR</div>	Andrew B. Kahng et al., Subwavelength Lithography and its Potential Impact on Design and EDA, 6 pages

EXAMINER <div style="text-align: center; font-size: 1.5em;">A. Fraser</div>	DATE CONSIDERED <div style="text-align: center; font-size: 1.5em;">7/30/03</div>
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* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next communication to applicant.